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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Appl. No.: 10/604,102

Applicant(s): Steegan et al.

Filed.: June 26, 2003

Art Unit: 2815

Dkt. No.: FIS920030051US1

Examiner: Eckert II, George C.

Title: **SELECTIVE SILICON-ON-INSULATOR ISOLATION STRUCTURES AND  
METHOD**

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Honorable Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**REQUEST FOR RECONSIDERATION**

This Request for Reconsideration is being filed in response to the Office Action mailed  
on February 28, 2005.

FIS920030055US1

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**CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)**

Applicant(s): Steegan et al.

Docket No.

FIS920030051US1

Application No. 10/604,102	Filing Date 6/26/2003	Examiner Eckert II, George C.	Group Art Unit 2815
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Invention: **SELECTIVE SILICON-ON-INSULATOR ISOLATION STRUCTURES AND METHOD**

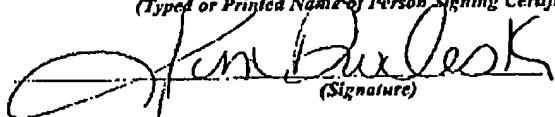
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